

Patent Abstracts of Japan

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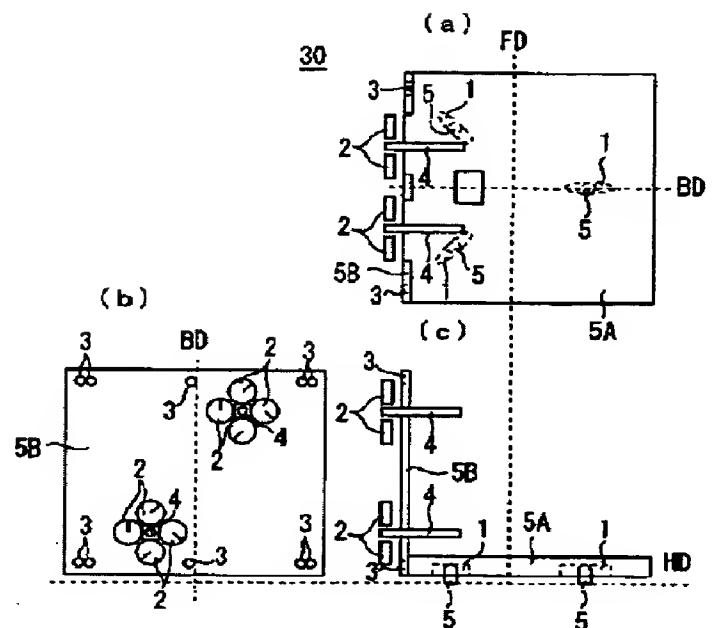
APPLICATION DATE : 31-05-00
 APPLICATION NUMBER : 2000162788

APPLICANT : SEMICONDUCTOR LEADING EDGE
 TECHNOLOGIES INC;

INVENTOR : FUJII ATSUHIRO;

INT.CL. : H01L 21/68

TITLE : LOAD PORT ADJUSTING TOOL,
 FOUP-MEASURING TOOL, FOUP
 WAFER PLANE MEASURING TOOL,
 KINEMATIC PIN SHAPE EVALUATING
 TOOL, KINEMATIC PIN POSITION
 EVALUATING TOOL, AND
 ADJUSTMENT/MEASUREMENT/EVALUATION
 METHOD USING THEM



ABSTRACT : PROBLEM TO BE SOLVED: To smooth the transfer of a substrate on the FIMS surface of a load port when manufacturing a semiconductor, improve switching reliability of a FOUP switching mechanism, and improve compatibility and switching reliability of an interface door.

SOLUTION: The position measurement mechanism for measuring a registration pin position on an FIMS surface, a position measurement mechanism for measuring the registration pin hole position of an FOUP door, a distance measurement mechanism for measuring distance from the FIMS surface to a front virtual reference surface, and the like are combined, thus obtaining a load port adjusting tool, an FOUP-measuring tool, and the like.

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